



To be submitted no later than January 31 of the year following the reporting period.
Submit to: psa@ansi.org.

**2010 Annual Report for the U.S. Technical Advisory Group (TAG)
To ISO 172 Optics and Photonics**
TC/SC/WG/PC # and title

Please provide the information requested herein in accordance with the requirements contained in 2.5.5 Maintenance of Accreditation as found in the *ANSI International Procedures*.

1. TAG Administrator Organization Name: **Optics and Electro-Optics Standards Council**
2. Scope of the U.S. TAG:

Standardization of terminology, requirements, interfaces and test methods in the field of optics and photonics.

This includes complete systems, devices, instruments, ophthalmic optics, optical and photonic components, auxiliary devices and accessories, as well as materials. Optics and photonics are used in the meaning of generation, handling and detection of optical radiation including signal processing.

Excluded :

Standardization for specific items in the field of cinematography (ISO/TC 36), photography (ISO/TC 42), eye protectors (ISO/TC 94), micrographics (ISO/TC 171), fibre optics for telecommunication (IEC/TC 86) and electrical safety of optical elements, and general lighting.

3. Please attach current TAG membership list, including: Name, affiliation, voting status, interest category and complete contact information for each member, including the Chair and other officers: **Attached, by SC**
4. Please provide the definitions of interest categories applicable to TAG members
General Interest
Producer
User/Industrial

5. Meetings:

- Dates and locations (domestic and international) of all meetings of the TAG, TC and/or SC that took place in the past year:
- If no meetings were held, please explain:
- Dates and locations of all meetings of the TAG, TC and/or SC scheduled for the upcoming year: **See individual SC reports, below**

6. If applicable, this confirms the status of Head of Delegation Reports for the past year:

- Not applicable, no international meetings were held
- Reports have already been submitted to ANSI
- Reports are attached
- Reports will be submitted by _____

7. Please list any problems encountered during the past year in the functioning of the U.S. TAG or U.S. TAG Administration, and any areas in which the U.S. TAG Administrator requires ANSI's assistance. *Note: for immediate assistance, please contact ISOT or psa@ansi.org.*

See individual SC reports, below.

8. Complaints/appeals:

- No complaints/appeals were submitted during this reporting period
- The following complaints/appeals were submitted during this reporting period; the status of each is described below:

9. Self-audits: Were any self-audits conducted?

- Yes, the results are attached
- No

10. Annual Compliance Forms: A TAG Compliance Form will be issued in January of each year. It must be returned in accordance with the established deadline to confirm that the TAG's procedures are in compliance with the current edition of the *ANSI International Procedures*. Overdue Compliance Forms and Annual Reports from previous years, as well as any revisions to the procedures under which the TAG is accredited, are required to be submitted to ANSI as a condition of maintaining accreditation. If you have not already done so, please submit them now to psa@ansi.org.

Certification Statement

I, the undersigned, on behalf of the U.S. TAG to ISO TC 172 certify that the TAG has been operating in a manner that complies with all applicable ANSI and ISO Procedures.

Dave Aikens
(Name of TAG Administrator)

Executive Director
(Title)

Optics and Electro-Optics Standards Council
(Organization)

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ATTACHMENTS:

ANSI/OEOSC TAG to ISO/TC172/SC1 Annual report for 2010

ANSI/OEOSC TAG to ISO/TC172/SC3 Annual report for 2010

ANSI/OEOSC TAG to ISO/TC172/SC4 Annual report for 2010

ANSI/OEOSC TAG to ISO/TC172/SC5 Annual report for 2010

ANSI/OEOSC TAG to ISO/TC172/SC7 Annual report for 2010

ANSI/OEOSC TAG to ISO/TC172/SC9 Annual report for 2010

Excel workbook - Roster of ANSI/OEOSC TAG to ISO/TC 172, by SC.

ANSI/OESC TAG to ISO/TC 172/SC 1 Annual Report for 2010

Prepared by TAG/SC 1 Leader: Dave Aikens

Number of Meetings Held during 2010: 1

Date: October 12, 2010

Location: BSR, London, England

Number of Meetings Scheduled for 2011: 1

Date: October 2011

Location: Kyoto, Japan

List any significant accomplishments for ANSI/OEOSC TAG/SC 1 this year.

In 2010, SC1 published four standards. Three of these, ISO 9336-1 on optical transfer function, ISO 10110-8 on surface texture notations, and ISO 15529 on MTF, were revisions to existing standards, and the fourth, ISO 25297-1, the NODIF information model, was a new standard. The United States led the revision of the first two standards.

More important, perhaps, was the decision to withdraw or cancel six projects, and begin work consolidating ISO 10110-2, 3, and 4 for glass imperfection notations, as well as many of the ISO 9022 Environmental standards. We view this reduction and consolidation as an important aspect of making standards affordable and relevant.

In addition, new projects have been initiated for a standard set of roughness artefacts, data reduction for roughness and waviness measurements on optics, fixing the OTF standard, and revising several parts of ISO 10110 (Parts 1, 10, 5, 6, and 12). Of these new projects, the United States is project leader on five of them, and is a primary contributor to the other three.

List any problems encountered by the ANSI/OEOSC TAG/SC 1 during the year

Not a problem so much as an observation. There is increasing resistance to revising the drawing notations standards to be more consistent with standard practice in the United States. Specifically in the areas of how glass is specified on drawings, and how surface imperfections are specified and evaluated, are being opposed by the German delegation. When this is combined with the Japanese agenda to not change anything unless there is no choice, and with the loss of active participation by the UK and France, we may not be successful in the coming years as we have been in the last five.

ANSI/OESC TAG to ISO/TC 172/SC 3 Annual Report for 2010

Prepared by TAG/SC 3 Leader: Gordon Boulton

Number of Meetings Held during 2010: 0

Date: N/A

Location: N/A

Number of Meetings Scheduled for 2010: 1

Location: Tokyo, Japan, October

List any significant accomplishments for ANSI/OEOSC TAG/SC 3 this year.

Provided US comments on WG 2 project to ISO CD 9211-4 for *Optical coatings — specific test methods*. This is a revision to the document and incorporates a draft amendment. The US chairs this project.

The US (JDSU) supplied samples for a comparison test of the cheesecloth abrasion tester pad preparation methodology.

List any problems encountered by the ANSI/OEOSC TAG/SC 3 during the year

As of the date of this report, none of the IR materials suppliers who have expressed an interest in participating in WG 3 have joined OEOSC.

ANSI/OEOSC TAG to ISO/TC172/SC4 Annual report for 2010

No report available at this time.

ANSI/OESC TAG to ISO/TC 172/SC 5 Annual Report for 2010

Prepared by TAG/SC 5 Leader: Lee Shuett

Number of Meetings Held during 2010: 1

Date: Sept 14-17

Location: Kyoto Japan

Number of Meetings Scheduled for 2011: 1

Date: September 20-23

Location: Washington, D.C.

List any significant accomplishments for ANSI/OEOSC TAG/SC 5 this year.

SC5 published no new standards published in 2010. At year end, SC5 was occupied with seven (7) Work Items included documents in various stages of completion: one (1) proof copy; two (2) at DIS stage; one (1) at Committee draft stage; three (3) at working draft stage. In addition, SC5 has eight (8) possible future projects under investigation.

The United States led the creation of a new standard ISO 19012 Optics and Photonics – Designation of microscope objectives; that will published in three parts. This standard brings international agreement on defining terminology of optical performance of microscope objectives which are critical to end users purchasing decisions. Prior to ISO 19012 the terminology was left entirely up to manufacturers to set their own guidelines, creating confusion and potential deception in the market. ISO 19012 Part 1: Flatness of field/plan, has already been published. 19012 Part 2: Chromatic Correction is in DIS stage. At the SC5 meeting in Kyoto, work continued on 19012 Part 3: Spectral Transmittance. When finished, this three part standard will unify critically important optical performance designations and will stand as some of the most important work to come out of SC5.

The United States also led the revision of ISO 8255-1 Cover glasses Part 1: dimensional tolerances, thickness and optical properties. As the resolution of biological light microscopes reaches the single molecule level of sensitivity, the requirements for the cover glass to match designers' specifications is essential. 8255-1 prior to revision did not agree with the US standard usage and the SC5 agreed to revise accordingly.

List any problems encountered by the ANSI/OEOSC TAG/SC 5 during the year

SC5 has struggled with our role in creation and maintenance of the ISO Concept Database. While we have been briefed by an SC5 member who also attends SC1 and works on the CDB, we are asking the Secretariat for more basic information on creation, usage, and maintenance.

ANSI/OEOSC TAG to ISO/TC172/SC7 Annual report for 2010

December 31, 2010

ISO/TC 172/SC 7 - Ophthalmic Optics and Instruments

Annual Report for 2010

Prepared by

Charles Campbell, SC7 US Delegation Leader

ISO/TC172/SC7 meetings in 2010

ISO/TC172/SC7 and its constituent working groups met on September 27 through October 1, 2010 in Las Vegas, Nevada, USA.

The Head of Delegation report for the Las Vegas meetings is attached to this report to give the details on the meetings held.

WG9 – Contact lenses –met on April 30, 2010 in Toronto, Canada.

Work of SC7 in 2010

During the course of the year the work of the various working groups, as represented by the documents prepared and voted on, was as follows;

NWIP (New Work Item Proposals) – 6

WG3– 1

WG7 – 4

WG9 - 1

CD (Committee Draft) - 4

WG3 disagree- 1

WG6 agree with comment – 1

WG8 agree - 1

WG9 agree–1

DIS (Draft International Standard) – 8

WG2 agree - 1

WG8 agree- 1

WG9 agree –3/ agree with comment - 2

WG10 disagree –1

FDIS (Final Draft International Standard) - 3

WG2 agree – 1

WG6 agree - 2

Systematic 5-year review – 4

WG2 – 1 abstain

WG6 – 2 confirm/1 revise

WG7 - 1 revise

It can be seen that the work of SC7 in 2010 includes work at all stages of the standardization process and similar to the activity of 2009. Only 4 issued standards came up for systematic review in 2009 compared with 19 in 2008.

Work by the various working groups within SC7

WG2 – Spectacle frames – Work, begun in 2007, on a new work item to create a standard for a spectacle frames electronic catalog and identification continued in 2010. This work is being done as a joint effort with WG8. When the Technical Method standard for nickel release determination in spectacle frame up for systematic review the United States abstained as this is not an issue of concern in any way in the United States.

WG3 – Spectacle lenses – A major issue being addressed by WG3 was the issue of transmission standards for spectacle lenses. A contentious issue arose having to do with the definition of the spectral band called UV A in that the spectacle lens industry uses a different value for the long wavelength limit than does CIE – the international organization that defined this spectral band in the first place. The spectacle lens group defines the spectral band of UV A as running from 315 nm to 380 nm whereas CIE defines the spectral band as running from 315 nm to 400 nm. This is primarily a commercial issue in that without special coatings glass spectacle lenses and some plastic materials used for spectacle lenses do not fully block radiation in the band 380 nm to 400 nm and the spectacle lens manufacturers would like to say that their lens block UV A and set limits in the spectacle lens transmission standard to support this view.

There is also work being done on a vocabulary for the spectacle lens standards but this has run into difficulty do to the fact that it appears an attempt is being made to write definition nominally for spectacle lenses and then insist that they be used throughout the ophthalmic optics field. There is resistance to this approach and at the Las Vegas meeting of SC7 it was resolved to revise the spectacle lens vocabulary standard in total and in so doing harmonize as well as can be done with other ophthalmic standards and their vocabularies. This will need to be watched carefully as it progresses.

WG6 - Ophthalmic instruments and test methods – Due to the fact that a number of projects within WG6 were brought to completion in 2009, the work of this working group was light in 2010. In 2011 a major revision of the fundamental standard for light hazard protection will commence. 4 International Standards resulting from WG6 work were published in 2010.

WG7 – Ophthalmic implants – The working group continues to work on the revision of various parts of the International Standard for intraocular lenses with the view of incorporating requirements for multifocal intraocular lenses and accommodating intraocular lenses – types of intraocular lenses that the current standard does not cover. Based on some reported problems with endotoxins that inadvertently made their way in some IV fluids and subsequently caused some eye inflammation following their use in ophthalmic surgery, the FDA became concerned about the tolerances for endotoxins found on intraocular lenses following manufacture. This issue continues to be under review by the working group.

One International Standard resulting from WG7 work was issued in 2010.

WG8 – Data Interchange – Work continued to create a standard for an electronic catalog for spectacle frames and their identification. This work is being done as a joint effort with WG2. The first part of this standard progressed through the DIS stage this year. The second part progressed through the CD stage to the DIS stage. A working draft has been created for the third part of this standard and will be submitted as Draft International Standard directly.

WG9 – Contact Lenses - WG9 decided to accept one of the two proposals offered by the Ad Hoc group formed to resolve the conflict between the standard for ophthalmometers and the contact lens standard for their use in measuring the surfaces of contact lenses. The contact lens standard in question will be revised to refer to the instrument standard for ophthalmometers and the ophthalmometer will be slightly revised by WG6 to accommodate the needs of the contact lens group.

There were 9 project groups with in WG9 in 2010. The United States provided the leadership in 7 of these 9 projects.

4 projects dealt with various matters having to do with contact lens care products. Work continued in the area of care solution compatibility with contact lens materials due to introduction into the business of silicon hydrogel materials. In

addition, due to ocular infections involving the acanthamoeba organism, much work has been devoted to devising an appropriate method of assessing the ability of various contact care solutions to provide protection against this disorder.

Work began on the revision of several parts of the 4 part standard for contact lenses.

One International Standard resulting from WG9 work was published in 2010.

WG10 - Devices for dioptric power measurement of lenses – the primary work of WG10, the revision of ISO 8598 – Focimeters, had progressed by the end of 2009 to the DIS stage for Part 1 of the standard – the portion dealing with general purpose focimeters. However, there were so many negative comments received during the voting process that at the Las Vegas meeting of WG10 it was decided that a second DIS needed to be prepared and circulated for vote. This had to be done quickly as the work was already on a termination time warning from the ISO Central Secretariat on this project. So the work of revision was completely done at the Las Vegas meeting. An unexpected difficulty arose at the meeting because convener – who is from China – could not get a U.S. travel visa and so could not attend the meeting. In her place, the meeting was led by Simon Pavy of Australia.

Work on Part 2 of the standard – the portion dealing with test lenses for focimeters – progressed through the New Work Item Proposal stage and this is now an active work item. A Committee Draft of Part 2 has been prepared and is in the voting stage.

ISO/TC172/SC7 publications in 2010

During 2010, 6 new International originating in SC7 were published. It came from the following working group.

WG6 4 standards

WG7 1 standard

WG9 1 standard

Organization of U.S. TAG for ISO/TC172/SC7

The process of voting for the various documents associated with the work of ISO TC172/SC7 was modified in 2010. So that all members of a TAG sub-group involved with voting on a document under the jurisdiction of that sub-group may see the opinions of other members of the sub-group and may see what the proposed U.S. response will be, this information is now posted on the OEOSC website. After the deadline date for the submission of opinion, the members of sub-group have a specified, limited time to comment to the sub-group leader before the U.S. position is submitted. To assist in the progress The Vision Council, the secretariat for ASC Z80 – Ophthalmic optics – volunteered to assist the OEOSC secretariat in the collection of this information and in communication with the various sub-group members. Amber Robinson of The Vision Council is providing this assistance. The process has been used over the course of the year with no difficulty other than the additional work this takes administratively.

Authorized participants to ISO/TC172/SC7 meetings

As noted in the Head of Delegation report, the presence of un-authorized persons in the role of un-invited observers from various companies in the United States at the Las Vegas meetings of ISO/TC172/SC7 prompted new rules for participants at all meetings of ISO/TC172/SC7 and its various working and project groups. These new rules are given in the attached resolutions of that meeting as Resolution 402. The U.S. TAG for ISO/TC172/SC7 will implement these new rules with the sub-group leaders deciding who shall be designated as an observer to any given meeting for their working group and associated project groups. The guidelines for making these choices will be formed by the leader and sub-group leaders in consultation with the ASC Z80 leadership.

Meetings for 2011

There is no scheduled meeting of ISO/TC172/SC7 in 2011. However, some of the project groups will meet and work will continue in general by correspondence.

ANSI/OEOSC TAG to ISO/TC172/SC9 Annual report for 2010

Prepared by TAG/SC 9 Leader: Thomas J. Lieb

Number of Meetings Held during 2010:

Number of Meetings Scheduled for 2011: 1 (WG only)

Date: January 2011

Location: WG 4 will meet During Photonics West. San Francisco, CA

List any significant accomplishments for ANSI/OEOSC TAG/SC 9 this year.

In 2010, SC9 processed one FDIS standards (IEC/ISO 11553-3 *Safety of machinery -- Laser processing machines -- Part 3: Safety requirements for Noise as a hazard*) and opened 5 systematic review processes on existing documents. The SC also resolved to adapt (exempt) the requirement for 5 P- members for acceptance of NWI's, since the P-member participation has reduced over the last several years. Additionally the SC voted negatively on ISO/DIS 11252: *Lasers and laser-related equipment Laser device Minimum requirements for documentation*; and urged the withdrawal of the standard.

2010 TC172/SC9 items for Systematic Review (5 items):

ISO 11151-1:2000 (vers 2): *Lasers and laser-related equipment -- Standard optical components -- Part 1: Components for the UV, visible and near-infrared spectral ranges*

ISO 11151-2:2000 (vers 2): *Lasers and laser-related equipment -- Standard optical components -- Part 2: Components for the infrared spectral range*

ISO 11810-2:2007: *Lasers and laser-related equipment -- Test method and classification for the laser-resistance of surgical drapes and/or patient-protective covers -- Part 2: Secondary ignition*

ISO 11553-2:2007: *Safety of machinery -- Laser processing machines -- Part 2: Safety requirements for hand-held laser processing devices*

ISO 13694:2000 (vers 2): *Optics and optical instruments -- Lasers and laser-related equipment -- Test methods for laser beam power (energy) density distribution*

List any problems encountered by the ANSI/OEOSC TAG/SC 9 during the year

An observation: There is steady decline in interest and participation in this work. This may be simply a reflection of the international economy over the last two years, or may exemplify that the market needs for these standards have been largely met (at least for the time being)

